

Title (en)  
Vacuum pump

Title (de)  
Vakuumpumpe

Title (fr)  
Pompe à vide

Publication  
**EP 2039941 A3 20160601 (DE)**

Application  
**EP 08016073 A 20080912**

Priority  
DE 102007044945 A 20070920

Abstract (en)  
[origin: EP2039941A2] The pump (100) has a gas inlet and a fast-rotating rotor (124), where the rotor is connected with a flange (118) of a multi-chamber vacuum system (101). The flange is provided with suction openings that are separated by a separating wall (106). A gas path separation structure is arranged in the gas inlet, where the structure is designed such that structure causes sealing of vacuum chambers (102, 103) of the multi-chamber vacuum system together with the separating wall. A central disk (129) forms the gas path separation structure together with bars (127, 128).

IPC 8 full level  
**F04D 19/04** (2006.01); **F04D 29/08** (2006.01); **F04D 29/42** (2006.01); **F04D 29/70** (2006.01)

CPC (source: EP US)  
**F04D 19/042** (2013.01 - EP US); **F04D 29/083** (2013.01 - EP US); **F04D 29/4213** (2013.01 - EP US); **F04D 29/701** (2013.01 - EP US)

Citation (search report)

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Designated contracting state (EPC)  
AT BE BG CH CY CZ DE DK EE ES FI FR GB GR HR HU IE IS IT LI LT LU LV MC MT NL NO PL PT RO SE SI SK TR

Designated extension state (EPC)  
AL BA MK RS

DOCDB simple family (publication)  
**EP 2039941 A2 20090325; EP 2039941 A3 20160601; EP 2039941 B1 20171108**; DE 102007044945 A1 20090409;  
US 2009092484 A1 20090409; US 8070418 B2 20111206

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**EP 08016073 A 20080912**; DE 102007044945 A 20070920; US 28419708 A 20080919